

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Abdurrahman Sezginer et al.

Application No.: NEW

Filed: HEREWITH

For: OVERLAY METROLOGY METHOD
AND APPARATUS USING MORE
THAN ONE GRATING PER
MEASUREMENT DIRECTION

Group Art Unit: Unknown

Examiner: Unknown

**INFORMATION DISCLOSURE
STATEMENT**

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San Francisco, CA 94105
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M/S PATENT APPLICATION

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Applicant(s) submit(s) herewith patents, publications or other information [attached hereto and listed on the attached Form PTO-1449 (modified)] of which they are aware, which they believe(s) may be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR § 1.56.

This Information Disclosure Statement:

- (a) ☒ accompanies the new patent application submitted herewith. 37 CFR § 1.97(a).
- (b) ☐ is filed within three months after the filing date of the application or within three months after the date of entry of the national stage of a PCT application as set forth in 37 CFR § 1.491.
- (c) ☐ as far as is known to the undersigned, is filed before the mailing date of a first Office Action on the merits, or before a first office action after filing a Request for Continued Examination under §1.114.
- (d) ☐ is filed after the first office action and more than three months after the application's filing date or PCT national stage date of entry filing but, as far as is known to the undersigned, prior to the mailing date of either a final rejection or a

Atty Docket No.: TWI-32410

notice of allowance, whichever occurs first, and is accompanied by either the fee (\$180) set forth in 37 CFR § 1.17(p) or a certification as specified in 37 CFR § 1.97(e), as checked below.

- (e) ☐ is filed after the mailing date of either a final rejection or a notice of allowance, whichever occurred first, and the Issue Fee has not been paid, and is accompanied by the fee (\$130) set forth in 37 CFR § 1.17(i)(1) and a certification as specified in 37 CFR § 1.97(e), as checked below. This document is to be considered as a petition requesting consideration of the information disclosure statement.

[If either of boxes (d) or (e) is checked above, the following "certification" under 37 CFR § 1.97(e) may need to be completed.] The undersigned certifies that:

- (f) ☐ Each item of information contained in the information disclosure statement was cited in a communication mailed from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this information disclosure statement.
- (g) ☐ No item of information contained in this information disclosure statement was cited in a communication mailed from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned after making reasonable inquiry, was known to any individual designated in 37 CFR § 1.56(c) more than three months prior to the filing of this information disclosure statement.

A list of the patent(s) or publication(s) is set forth on the attached Form PTO-1449 (Modified).

A copy of the items on PTO-1449 (Modified) is supplied herewith:

- (h) ☒ each (i) ☐ none (j) ☐ only those listed below:

Those patent(s) or publication(s) which are marked with an asterisk (*) in the attached form PTO-1449 (Modified) are not supplied because they were previously cited by or submitted to the Office in a prior application no. _____, filed _____ and relied upon in this application for an earlier filing date under 35 U.S.C. § 120.

A concise explanation of relevance of the items listed on form PTO-1449 (Modified) is:

- (k) ☒ not given
- (l) ☐ given for each listed item

- (m) ☐ given for only non-English language listed item(s) [Required]
- (n) ☐ is in the form of an English language copy of a Search Report from a foreign patent office, issued in a counterpart application, which refers to the relevant portions of the references [copy attached].

The Examiner is reminded that a "concise explanation of the relevance" of the submitted items "may be nothing more than identification of the particular figure or paragraph of the patent or publication which has some relation to the claimed invention," MPEP § 609.

While the information and references disclosed in this Information Disclosure Statement may be "material" pursuant to 37 CFR § 1.56, it is not intended to constitute an admission that any patent, publication or other information referred to therein is "prior art" for this invention unless specifically designated as such.

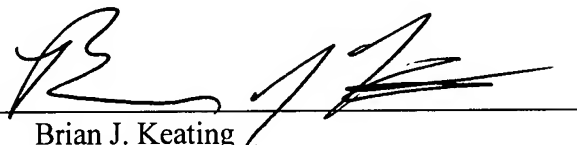
In accordance with 37 CFR § 1.97(g), the filing of this Information Disclosure Statement shall not be construed to mean that a search has been made or that no other material information as defined in 37 CFR § 1.56(a) exists. It is submitted that the Information Disclosure Statement is in compliance with 37 CFR § 1.98 and MPEP § 609 and the Examiner is respectfully requested to consider the listed references.

Respectfully submitted,

STALLMAN & POLLOCK LLP

Dated: July 3, 2003

By:


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Attorneys for Applicant(s)

INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>	Docket Number (Optional) TWI-32410	Application Number NEW
	Applicant(s) Abdurrahman Sezginer et al.	
	Filing Date HEREWITH	Group Art Unit Unknown

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	AA	US 2002/0135875	09/26/2002	Niu et al.	359	564	02/27/2001
	AB	US 2002/0158193	10/31/2002	Sezginer et al.	250	237	02/12/2002
	AC	US 2003/0042579	03/06/2003	Schulz	257	629	04/29/2002
	AD	US 2003/0043372	03/06/2003	Schulz	356	327	04/29/2002
	AE	US 2003/004702	03/06/2003	Schulz	430	30	04/29/2002
	AF	6,532,076	03/11/2003	Sidorowich	356	630	04/04/2000

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	AG	WO 02/25723 A2	03/28/2002	PCT	H01L	21/66		

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

	AH	W. Yang et al., "A Novel Diffraction Based Spectroscopic Method For Overlay Metrology," <i>SPIE's 28th Annual International Symposium and Education Program and Microlithography</i> , February 2003, pp. 9.
	AI	T.A. Germer, "Measurement of lithographic overlay by light scattering ellipsometry," <i>Proceedings of SPIE</i> , Surface Scattering and Diffraction and Advanced Metrology II, Vol. 4780, 2002, pp. 72-79.
	AJ	H.T. Huang et al., "Scatterometry-Based Overlay Metrology," <i>SPIE (Microlithography 2003)</i> , Vol. 5038, 2003. 12 pages in length.
	AK	M. Adel et al., "Characterization of Overlay Mark Fidelity," <i>SPIE Meeting on MicroLithography</i> , February 2003, 8 pages in length.

Examiner	Date Considered
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	